## IN THE CLAIMS:

Please cancel claims 15, 19, 20, 49, 58, and 59 and amend the claims as follows.

1. (Currently Amended) A method of treating a substrate surface comprising copper or a copper alloy, the method comprising:

applying to the substrate surface a composition comprising:

one or more chelating agents, wherein the one or more chelating agents comprise an acid and a base;

one or more pH adjusting agents to produce a pH between about 3 and about 11; and

deionized water; and

a reducing agent, wherein the reducing agent comprises between about 0.01 wt.% and about 20 wt.% of the composition; and then applying a corrosion inhibitor solution.

- 2. (Original) The method according to claim 1, further comprising treating the substrate surface with a corrosion inhibitor solution prior to treating the substrate surface with the composition.
- 3. (Original) The method according to claim 2, wherein the corrosion inhibitor solution comprises between about 0.01 wt.% and about 0.50 wt.% corrosion inhibitor and deionized water.
- 4. (Original) The method according to claim 3, wherein the corrosion inhibitor is selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.
- 5. (Cancelled)

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- 6. (Original) The method according to claim 1, wherein the one or more chelating agents comprising an acid has a concentration of up to about 40 wt.% of the composition.
- 7. (Original) The method according to claim 6, wherein the acid is a carboxylic acid having one or more acid groups.
- 8. (Original) The method according to claim 7, wherein the acid is selected from the group consisting of acetic acid, citric acid, maleic acid, and combinations thereof.
- 9. (Original) The method according to claim 1, wherein the one or more chelating agents comprising a base has a concentration up to about 5 wt.% of the composition.
- 10. The method according to claim 1, wherein the base comprises (Original) between about 0.5 wt.% and about 3 wt.% of the composition.
- 11. (Original) The method according to claim 9, wherein the base is selected from the group consisting of ammonium hydroxide, ammonium hydroxide derivatives, amines, and combinations thereof.
- 12. (Original) The method according to claim 1, wherein the composition further comprises a corrosion inhibitor.
- 13. (Original) The method according to claim 12, wherein the corrosion inhibitor comprises between about 0.01 wt.% and about 0.50 wt.% of the composition.
- 14. (Original) The method according to claim 12, wherein the corrosion inhibitor is selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.

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## 15. (Canceled)

- 16. (Original) The method according to claim 1, wherein the composition has a pH between about 4 and about 5 and comprises between about 5 wt.% and about 30 wt.% citric acid, between about 0.5 wt.% and about 3.0 wt.% ammonium hydroxide.
- 17. The method according to claim 2, wherein the corrosion inhibitor (Original) solution is applied prior to treating the substrate surface with the composition for between about 3 and about 10 seconds.
- 18. (Original) The method according to claim 1, wherein the composition is applied between about 10 and about 20 seconds.

19-20. (Canceled)

21. (Currently Amended) The method according to claim 19 A method of treating a substrate surface comprising copper or a copper alloy, the method comprising:

applying to the substrate surface a composition comprising:

one or more chelating agents, wherein the one or more chelating agents comprise an acid and a base:

one or more pH adjusting agents to produce a pH between about 3 and about 11;

a reducing agent wherein the reducing agent is selected from the group consisting of hydroxylamine, glucose, sulfothionate, potassium iodide, and combinations thereof; and

deionized water; and then applying a corrosion inhibitor solution. 08:49pm

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22. The method according to claim 1, wherein the corrosion inhibitor (Original) solution comprises between about 0.01 wt.% and about 0.50 wt.% corrosion inhibitor and deionized water.

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- 23. The method according to claim 22, wherein the corrosion inhibitor is (Original) selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.
- 24. (Original) The method according to claim 22, wherein the corrosion inhibitor solution is applied between about 3 and about 10 seconds.
- 25. (Original) The method according to claim 1, wherein the one or more pH adjusting agents are selected from the group consisting of a non-oxidating inorganic acid, a non-oxidating organic acid, a non-oxidating inorganic base, a non-oxidating organic base, and combinations thereof.
- 26. The method according to claim 1, wherein the one or more pH (Original) adjusting agents comprise an acidic chelating agent, a basic chelating agent or a combination thereof.
- 27. (Currently Amended) A method of planarizing a substrate containing an dielectric layer having an upper surface and at least one opening, a barrier layer lining the opening and the upper surface of the dielectric layer, and copper or a copper alloy filling the opening and on the dielectric layer, the method comprising:

removing the copper or copper alloy layer and the barrier leaving an exposed substrate surface comprising copper or copper alloy in the opening; and

treating the exposed substrate surface comprising copper or the copper alloy by applying thereto a composition comprising

one or more chelating agents,

one or more pH adjusting agents to produce a pH between about 3 and about 11, and

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deionized water,

wherein the one or more chelating agents comprise an acid and a base and

wherein the composition further comprises a reducing agent, wherein the reducing agent comprises between about 0.01 wt.% and about 20 wt.% of the composition; and

then applying a corrosion inhibitor solution.

- 28. (Original) The method according to claim 27, further comprising removing the barrier layer after removing the copper or copper alloy layer and prior to chemically treating the exposed substrate surface.
- 29. (Original) The method according to claim 27, wherein removing the copper or the copper alloy layer comprises chemical-mechanical polishing (CMP) the copper or the copper alloy layer.
- 30. (Original) The method according to claim 29, wherein the method comprises: removing the copper or copper alloy layer and stopping on the barrier layer; removing the barrier layer and leaving the exposed substrate surface comprising copper or copper alloy features.
- 31. (Original) The method according to claim 27, wherein: the dielectric layer comprises a silicon oxide; and the barrier layer comprises tantalum (Ta) or tantalum nitride (TaN).
- 32. (Original) The method according to claim 27, wherein the method comprises chemically treating the exposed substrate surface comprising copper or the copper alloy layer to remove a portion of the substrate surface of the copper or copper alloy or to remove corrosion stains from the copper or copper alloy substrate surface.

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- 33. (Original) The method according to claim 32, wherein the method comprises chemically removing up to about 50Å from the exposed substrate surface comprising copper or the copper alloy.
- 34. (Original) The method according to claim 27, further comprising treating the substrate surface with a corrosion inhibitor solution prior to applying the composition.
- 35. (Original) The method according to claim 27, wherein the composition comprises deionized water, citric acid and ammonium hydroxide.
- 36. (Original) The method according to claim 27, wherein the method comprises: mounting the substrate on a carrier in a CMP apparatus; CMP the substrate using a polishing pad; performing the initial treating step; applying the composition; and applying the corrosion inhibitor solution while separating the substrate from the polishing pad.
- 37. (Original) The method according to claim 34, wherein the corrosion inhibitor solution comprises between about 0.01 wt.% and about 0.50 wt.% corrosion inhibitor and delonized water.
- 38. (Original) The method according to claim 37, wherein the corrosion inhibitor is selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.
- 39. (Cancelled)

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- 40. (Original) The method according to claim 27, wherein the one or more chelating agents comprising an acid has a concentration of up to about 40 wt.% of the composition.
- 41. (Original) The method according to claim 40, wherein the acid is a carboxylic acid having one or more acid groups.
- 42. (Original) The method according to claim 41, wherein the acid is selected from the group consisting of acetic acid, citric acid, maleic acid, and combinations thereof.
- 43. (Original) The method according to claim 27, wherein the base comprises up to about 5 wt.% of the composition.
- 44. (Original) The method according to claim 43, wherein the base comprises between about 0.5 wt.% and about 3 wt.% of the composition.
- 45. (Original) The method according to claim 43, wherein the base is selected from the group consisting of ammonium hydroxide, ammonium hydroxide derivatives, amines, and combinations thereof.
- 46. (Original) The method according to claim 27, wherein the composition further comprises a corrosion inhibitor.
- 47. (Original) The method according to claim 46, wherein the corrosion inhibitor comprises between about 0.01 wt.% and about 0.50 wt.% of the composition.
- 48. (Original) The method according to claim 46, wherein the corrosion inhibitor is selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.

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## 49. (Canceled)

- 50. (Original) The method according to claim 49, wherein the composition has a pH between about 4 and about 5 and comprises between about 5 wt.% and about 30 wt.% citric acid, between about 0.5 and about 3.0 wt.% ammonium hydroxide.
- 51. (Original) The method according to claim 34, wherein the corrosion inhibitor solution is applied between about 3 and about 10 seconds prior to treating the substrate surface with the composition.
- 52. (Original) The method according to claim 27, wherein the composition is applied between about 10 and about 20 seconds.
- 53. (Original) The method according to claim 34, wherein the corrosion inhibitor solution comprises between about 0.01 wt.% and about 0.50 wt.% corrosion inhibitor and deionized water.
- 54. (Original) The method according to claim 34, wherein the corrosion inhibitor is selected from the group consisting of benzotriazole, 5-methyl-1-benzotriazole, and combinations thereof.
- 55. (Original) The method according to claim 27, wherein the corrosion inhibitor solution is applied between about 3 and about 10 seconds.
- The method according to claim 27, wherein the pH adjusting agent 56. (Original) is selected from the group consisting of a non-oxidating Inorganic acid, a non-oxidating organic acid, a non-oxidating inorganic base, a non-oxidating organic base, and combinations thereof.

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57. (Original) The method according to claim 27, wherein the one or more pH adjusting agents comprise an acidic chelating agent, a basic chelating agent or a combination thereof.

58-59. (Canceled)

60. (Currently Amended) The method according to claim 58 A method of planarizing a substrate surface containing a dielectric layer having an upper surface and at least one opening, a barrier layer lining the opening and the upper surface of the dielectric layer, and copper or a copper alloy filling the opening on the dielectric layer, the method comprising:

removing the copper or copper alloy layer and the barrier leaving an exposed substrate surface comprising copper or copper alloy in the opening; and

treating the exposed substrate surface comprising copper or the copper alloy by applying thereto a composition comprising one or more chelating agents, one or more pH adjusting agents to produce a pH between about 3 and about 11, a reducing agent, and deionized water, wherein the one or more chelating agents comprise an acid and a base and wherein the reducing agent is selected from the group consisting of hydroxylamine, glucose, sulfothionate, potassium iodide, and combinations thereof; and then applying a corrosion inhibitor solution.

61. (Currently Amended) The method of claim 1 A method of treating a substrate surface comprising copper or a copper alloy, the method comprising:

applying to the substrate surface a composition comprising:

one or more chelating agents, wherein the one or more chelating agents comprise an acid and a base;

one or more pH adjusting agents to produce a pH between about 3 and about 11; and

deionized water; and then

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applying a corrosion inhibitor solution, wherein the composition comprises about 26 wt.% citric acid, about 3 wt.% ammonia, deionized water, and a pH of about 4.

62. (Currently Amended) The method of claim 27 A method of planarizing a substrate surface containing an dielectric layer having an upper surface and at least one opening, a barrier layer lining the opening and the upper surface of the dielectric layer, and copper or a copper alloy filling the opening and on the dielectric layer, the method comprising:

removing the copper or copper alloy layer and the barrier leaving an exposed substrate surface comprising copper or copper alloy in the opening; and

treating the exposed substrate surface comprising copper or the copper alloy by applying thereto a composition comprising one or more chelating agents, one or more pH adjusting agents to produce a pH between about 3 and about 11, and deionized water, wherein the one or more chelating agents comprise an acid and a base; and then applying a corrosion inhibitor solution, wherein the composition comprises about 26 wt.% citric acid, about 3 wt.% ammonia, deionized water, and a pH of about 4.